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U.S. PTO

U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10025144	12/18/2001	438	633	28/3	Smoot

APPLICANTS: Moon Yongsik; Mai David; Wijekoen Kapile; Bajaj Rajeev; Surana Raul; Hu Yongqi; Kaushal Tony; Li Shijian; Li Jui-Lung; Wang Shi-Ping; Lam Gary; Ratnaker Fred;

* CONTINUING DATA VERIFIED: *S.W.S.*
THIS APPLN CLAIMS BENEFIT OF 60/304,543 07/11/2001

** FOREIGN APPLICATIONS VERIFIED: None *S.W.S.*

PG-PUB DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	AMAT/5803/CMP/CMP/RKK
Verified and Acknowledged Examiner's initials <i>S.W.S.</i>		U.S. DEPT. OF COMM /PAT. & TM-PTO-436L (Rev. 12-95)
TITLE : Method and apparatus for polishing metal and dielectric substrates		

NOTICE OF ALLOWANCE MAILED *7/29/03*

ISSUE FEE

Amount Due *\$1600* Date Paid

TERMINAL DISCLAN

DRAWINGS		CLAIMS ALLOWED	
Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims
			Print Claim for O.G.
NOTICE OF ALLOWANCE MAILED			
ISSUE FEE			
Amount Due	Date Paid	ISSUE BATCH NUMBER	
(Primary Examiner) _____	(Date) _____	(Legal Instruments Examiner) _____ (Date) _____	